

FORM 1449 INFORMATION DISCLOSURE STATEMENT IN AN APPLICATION (Use several sheets if necessary)	Docket Number: 10467.43US12	Application Number: 10/751,091
	Applicant: MOECKLY ET AL.	
	Filing Date: 01/02/2004	Group Art Unit: 1755

U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>PN</i>	2004/0134967 A1	07/15/2004	Moeckly et al.			

FOREIGN PATENT DOCUMENTS							
	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)		
<i>PN</i>		Char, K. et al., "High T_c superconductor-normal-superconductor Josephson junctions using CaRuO_3 as the metallic barrier," <i>Applied Physics Letters</i> , Vol. 62, No. 2, pp. 196-198 (January 11, 1993)
<i> </i>		Harada, K. et al., "Fabrication of All-High- T_c Josephson Junction Using As-Grown $\text{YBa}_2\text{Cu}_3\text{O}_x$ Thin Films," <i>Japanese Journal of Applied Physics</i> , Vol. 30, No. 8A, Part 2, pp. L1387-1389 (August 1, 1991)
<i> </i>		Huang, Y. et al., "The effect of microstructure on the electrical properties of YBCO interface-engineered Josephson junctions," <i>Physica C</i> , Vol. 314, pp. 36-42 (1999)
<i> </i>		Makita, T. et al., "Fabrication of Ramp-Edge Junction with $\text{NdBa}_2\text{Cu}_3\text{O}_y$ -Based Interface-Modified Barrier," <i>Jpn. J. Appl. Phys.</i> , Vol. 39, Part 2, No. 7B, pp. L730-L732 (July 15, 2000)
<i> </i>		Makita, T. et al., "Fabrication and Characterization of Y-Ba-Cu-O and Nd-Ba-Cu-O Ramp-Edge Junctions with an Interface-Modified Barrier," <i>IEEE Transactions on Applied Superconductivity</i> , Vol. 11, No. 1, pp. 155-158 (March 2001)
<i>↓</i>		Moeckly, B. et al., "Interface-Engineered High- T_c Josephson Junctions," <i>Applied Superconductors</i> , Vol. 6, Nos. 7-9, pp. 317-323 (1998)

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EXAMINER <i>PN Watters</i>	DATE CONSIDERED <i>07/17/07</i>
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form for next communication to the Applicant.	

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FORM 1449 INFORMATION DISCLOSURE STATEMENT IN AN APPLICATION (Use several sheets if necessary)	Docket Number: 10467.43US12	Application Number: 10/751,091
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U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
WJ	4,916,116	04/10/1990	Yamazaki			
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	5,077,270	12/31/1991	Takeda et al.			
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	5,904,861	05/1999	Ban et al.			

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DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
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WJ	"Poster Sessions", <i>Source Unknown</i> , pg. 109 (1994)
	Agostinelli, J. et al., "Cubic Phase in the Y-Ba-Cu-O System", <i>Physical Review B</i> , Vol. 43, No. 13, pp. 11 396-11 399 (May 1991)
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	Char, K. et al., "Crystal Interface Engineering In High T _c Oxides" <i>MRS Bulletin</i> , pp. 51-55 (September 1994).
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	Heinsohn, J. et al., "Current transport in ramp-type junctions with engineered interface," <i>Journal of Applied Physics</i> , Vol. 89, No. 7, pp. 3852-3860 (April 1, 2001).

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<i>PW</i>	Hunt, B. et al., "High Temperature Superconductor Josephson Weak Links", <i>Second Symposium on Low Temperature Electronics and High Temperature Superconductivity, Electrochemical Society Meeting, Honolulu, Hawaii</i> , Vol. 93-22, pp. 467-472 (May 1993).
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<i>W</i>	Wu, Y. et al., "Structural variation of the interface-engineered layers in YBa ₂ Cu ₃ O _{7.4} thin films," <i>Physica C</i> , Vol. 366, pp. 51-56 (2001).





EXAMINER <i>Paul W. W. W.</i>	DATE CONSIDERED <i>7/17/07</i>
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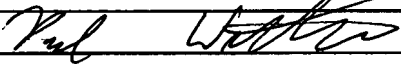
Sheet 3 of 3

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	Yoshida, J., "Recent Progress of High-Temperature Superconductor Josephson Junction Technology for Digital Circuit Applications," <i>IEICE Trans. Electron.</i> , Vol. E83-C, No. 1, pp. 49-59 (January 2000).
	Yoshida, J. et al., "Current transport in interface-engineered high-T _c Josephson junctions," <i>Physica C</i> , Vol. 367, pp. 260-266 (2002).
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